		2003/02/06 15:19	USPAT	bypass near deposition near chamber	0	BRS	89
		2003/02/06 15:05	USPAT	"5534309" and aerosol and bypass	0	BRS	67
		2003/02/06 15:05	USPAT	"5534309" and aerosol	8	BRS	66
		2003/02/06 13:27	USPAT	("5534309").PN.	1	IS&R	65
		2003/02/06 15:05	USPAT	"5534309" and impact\$3	ω	BRS	64
		2003/02/06 10:20	USPAT	"5534309"	15	BRS	63
		2003/02/06 10:18	USPAT	("5534309").PN.	1	IS&R	62
		2003/02/05 09:25	US-PGPUB	deposition same aerosol same nozzle	23	BRS	61
		2003/02/04 14:31	USPAT	<pre>(wafer and aerosol same solid) and deposit\$3 same solid same wafer</pre>	13	BRS	60
		2003/02/04 14:31	USPAT	<pre>(wafer and aerosol same solid) and deposit\$3 same solid</pre>	58	BRS	59
1		2003/02/04 14:30	USPAT	wafer and aerosol same solid	134	BRS	58
		2003/02/04 14:07	USPAT	(118/52,612).CCLS.	868	IS&R	57
3 3 3 3 3 3 3 3 3 3 3 3 3 3 3 3 3 3 3 3		2003/02/04 14:07	USPAT	(118/319,320).CCLS.	799	IS&R	56
		2003/02/04 14:23	USPAT	((118/308).CCLS.) and aerosol	15	BRS	55
		2003/02/04 14:03	USPAT	((118/308).CCLS.) and dry near gas	ω	BRS	54
		2003/02/04 14:02	USPAT	(118/308).CCLS.	1028	IS&R	53
		2002/08/20 15:23	USPAT	(427/240,585,99).CCLS.	1692	IS&R	52
		2002/08/20 15:11	USPAT	(118/309,326).CCLS.	1189	IS&R	51
Error Definition	Comments	Time Stamp	DBs	Search Text	Hits	Тўре	

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02/10/2003, EAST Version: 1.03.0007

	Туре	Hits	Search Text	DBs	Time Stamp	Comments	Error Definition
69	BRS	18	bypass with deposition near chamber	USPAT	2003/02/06 15:31		
70	BRS	6124	deposition near chamber	USPAT	2003/02/06 15:32		
71	BRS	7340	deposition near chamber	USPAT; US-PGPUB	2003/02/06 15:32		
72	BRS	65	(deposition near chamber) and (CNC or (particle near counter))	USPAT; US-PGPUB	2003/02/06 15:33		
73	BRS	F F	5746832.URPN.	USPAT	2003/02/06 16:05	***************************************	
74	BRS	0	pair same pressure same sensor\$1 same DMA	USPAT	2003/02/07 15:05		
75	BRS	4937	pair same pressure same sensor\$1	USPAT	2003/02/07 15:06		
76	BRS	172	pair near pressure near sensor\$1	USPAT	2003/02/07 15:06		
77	BRS	22	<pre>(pair near pressure near sensor\$1) and (wafer or semiconductor)</pre>	USPAT	2003/02/07 15:07		
78	BRS	15	(orifice\$1 or(flow near restrict\$3)) same DMA	USPAT	2003/02/07 15:45	***************************************	
79	BRS	2	<pre>(orifice\$1 or(flow near restrict\$3)) same DMA same vacuum</pre>	USPAT	2003/02/07 15:20		

